

Contents

1	Introduction	1
1.1	Overview of Diamond	1
1.2	Synthetic Diamond	2
1.2.1	High Pressure and High Temperature Synthesis of Diamond	3
1.2.2	Chemical Vapour Deposition of Diamond	4
1.3	Polishing of Diamond surfaces	7
	References	8
2	Understanding the Material Removal Mechanisms	11
2.1	Conversion of Diamond to Non-Diamond Carbon	11
2.2	Micro-Cleavage	15
2.3	Diffusion of Carbon to Soluble Metals	16
2.4	Chemical Reactions	17
2.5	Evaporation and Sputtering	20
2.6	Summary of the Polishing Pathways	21
	References	22
3	Mechanical Polishing	25
3.1	Polishing Technique and Equipment	25
3.2	Polishing of Single Crystalline Diamond	27
3.2.1	Orientation and Direction of Polishing	27
3.2.2	Material Removal Rate	28
3.2.3	Quality of Polished Surfaces	32
3.3	Polishing of Polycrystalline Diamond	32
3.4	Polishing of CVD Diamond Films	36
3.5	Polishing Mechanisms	37
3.6	Techniques to Improve the Polishing Rate of Mechanical Polishing	41
	References	42

4 Chemo-Mechanical Polishing	45
4.1 Equipment	45
4.2 Polishing Principle	47
4.3 Material Removal Rate and Polishing Temperature	47
4.4 Surface Finish	51
4.5 Optimization of Polishing Process	53
References	55
5 Thermo-Chemical Polishing	57
5.1 Thermo-Chemical Polishing with Hot Metal Plate	57
5.1.1 Polishing Set Up	58
5.1.2 Polishing Rate and Surface Quality	59
5.1.3 Material Removal Mechanisms	64
5.2 Polishing with Molten Catalytically Active Metals	70
5.2.1 Polishing Setup and Metal/Alloy Selection	70
5.2.2 Polishing Efficiency and Surface Quality	72
References	75
6 High Energy Beam Polishing	79
6.1 Laser Polishing	79
6.1.1 Polishing Conditions	80
6.1.2 Material Removal Rate and Surface Finish	81
6.1.3 Material Removal Mechanisms	85
6.1.4 Applications	87
6.2 Ion Beam Polishing	88
References	92
7 Dynamic Friction Polishing: Process and Modeling	95
7.1 Polishing Equipment	95
7.2 Interface Temperature	97
7.3 Polishing Conditions	101
7.4 Establishing the Polishing Map	104
7.5 Modeling of Polishing Efficiency	107
References	109
8 Dynamic Friction Polishing: Characterization and Material Removal Mechanisms	111
8.1 Surface Characterization	111
8.1.1 Surface Generation	112
8.1.2 Composition and Structural Analysis	113
8.1.3 Underlying Mechanism of Cracking	119
8.2 Analysis of Polishing Debris	120

8.3	Analysis of Cross-Sectional Polished PCD Composites	124
8.3.1	Microanalysis	125
8.3.2	Nanoanalysis	125
8.4	Material Removal Mechanisms	127
	References	129
9	Dynamic Friction Polishing: Applications	133
9.1	Polishing of Single Crystal Diamond	133
9.2	Polishing of PCD Composites	135
9.3	Polishing of CVD Diamond Films	137
9.3.1	Free-standing CVD Diamond Wafers	137
9.3.2	CVD Diamond Thin Films	141
	References	143
10	Other Polishing Techniques	145
10.1	Electrical Discharge Machining	145
10.2	Abrasive Liquid Jet Polishing	150
10.3	Aero-lap Polishing	151
10.4	Precision Polishing Diamond by Reaction with Copper	153
10.5	Miscellaneous Polishing Techniques	154
	References	155
11	Applicability of Individual Techniques	157
11.1	Comparison of Polishing Techniques	157
11.2	Selection of Polishing Techniques	162
11.3	Some Open Problems	163
	References	164
	Authors Biography	165
	Index	167

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